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7/18/03  
PATENT DBell

Customer No. 22,852  
Attorney Docket No. 04329.2555

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
)  
Hiroshi NOMURA ) Group Art Unit: 2877  
)  
Application No.: 09/816,164 ) Examiner: G. Stock Jr.  
)  
Filed: March 26, 2001 )  
)  
For: METHOD OF MEASURING )  
DISPLACEMENT OF OPTICAL )  
AXIS, OPTICAL MICROSCOPE )  
AND EVALUATION MARK )

Commissioner for Patents  
Washington, DC 20231

Sir:

**AMENDMENT**

In reply to the Office Action dated March 28, 2003, the period for reply extending to June 30, 2003 (June 28, 2003 being a Saturday), please amend the application as follows:

**IN THE ABSTRACT:**

Please amend the Abstract as follows:

A method of measuring the displacement of the optical axis of an optical microscope having an illumination optical system and a projection optical system includes a step of irradiating the evaluation mark having diffraction grating patterns formed on a substrate with illumination light by way of the illumination optical system and observing the evaluation mark by way of the projection optical system to obtain the

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FINNEGAN  
HENDERSON  
FARABOW  
GARRETT &  
DUNNER LLP

1300 I Street, NW  
Washington, DC 20005  
202.408.4000  
Fax 202.408.4400  
www.finnegan.com